

Precision Metrology Lab ME Dept. NTU

Person in charge: Kuang-Chao Fan, PhD Lifetime Distinguished Professor Fellow of SME, CSME, CIAE

Lab Introduction

This laboratory was established in 1984 by Prof. Fan, specialized in teaching and research on dimensional measurements from macro to micro and nano scales.

Course offered: Precision Metrology, Precision Engineering Design, Machine Tools, Automatic Optical Inspection.

Equipments: 6 Laser interferometers for length measurement,

4 3D microscopes (one white light, one confocal, one holographic and one stereo) for micro/nano profile measurements,

3 contact profilers (one roughness, one profile and one roundness) for geometrical measurements,

3 non-contact image apparatus for optical dimension measurements.

A range of gauges and meters is available for general dimensional inspection.

A number of self-developed sensors are also available for industrial on-line measurements, such as displacement, angle, force, acceleration, level, flatness, etc.

This Lab has the capability to design customized measurement equipment for particular use that cannot be purchased from the market or the market price is too high.



Current Researches

- 1. Development of a Micro/nano-CMM
- 2. Development of miniature interferometers as builtin sensors for precision machines
- 3. Chromatic confocal microscope
- 4. Machine tool metrology



1. Development of a Micro/nano-CMM



Micro-CMM at NTU Taiwan (2011)



J of Nanomanufacturing (2011)



Core Technology: Nano-motion

Nanomotion Ultrasonic Motor











Reconfigurable Interferometric Module

Core module





2-D high precision coplanar stage (2012)

Introduction:

- Conventional XY stage is stacked up by two linear stages. The Abbé error of the lower stage is high. An innovation coplanar stage is thus proposed in this study.
- The stage motion is actuated by a ultrasonic motor, the opposite side is the motion sensor of MDFS.

MI+AC

Table

LRM

Base

MI +

AC





Motion control of a coplanar stage

Introduction:

• This research presents the motion control of a coplanar stage which is driven by ultrasonic motors. Applying the self-tuning neuro-PID controller to control the displacement and speed of the coplanar stage, any contouring path of any geometry could be achieved.





Proc. ISPEMI (2011)



Z-axis Spindle and Probe Pesign









Pagoda Bridge



Reality





3. Chromatic confocal microscope





Enlarge measuring range CCD for full field image



Measurement Under Vibration





Video show



Confocal microscope system



Introduction:

- Based on confocal theorem and Snell's law, a long measuring range confocal microscope system is being developed to measure the thickness and refractive index of transparent thin film.
- The vertical scan module is sensed by a miniature Michelson interferometer.

$$T = \frac{\delta f}{1 - \sqrt{\frac{n_1^2 - NA^2}{n_2^2 - NA^2}}} \qquad n_2^2 = \frac{1 - NA^2 + (\frac{T - \delta f}{T})^2 NA^2}{(\frac{T - \delta f}{T})^2}$$





4. Machine tool metrology



Prediction of Machine Tool Slideway Wear

Introduction:

• After a long period of cutting operations, any machine tool will appear obvious wear on the slideways. Such a wear will degrade the accuracy of the machine tool due to the increase of angular errors yielding to serious Abbé errors. This research proposes a mathematical model so that at given cutting forces and parameters of the slideway it is able to calculate the geometric errors of the slider due to contact deformation caused by the wear of the slideway and then predict the machining errors after a long-term operation.



Machining Error

Machine tool chatter suppression system

Introduction:

- This research presents a method to control the spindle speed for chatter suppression during cutting. A MEMS accelerometer is used to acquire the vibration signal during cutting. A band-pass filter is used to obtain the bandwidth of self-excited vibration signals, and the microcontroller is employed as the control unit of the chatter suppression system.
- The standard deviation of acceleration is calculated and compared to the chatter threshold value. Whenever the calculated standard deviation is larger than the chatter threshold value, the control unit will actively adjust the spindle speed by fuzzy incremental PI control scheme.







Abbé error compensator







Current NC Control Loop



Problem: feedback position is not the commanded position Abbé error is inevitable





Problem:

How to design a miniature and low cost 3-axis angle sensor?

How to integrated the Abbé error compensator into current NC controller?





Design of a roll angle sensor





3-axis Angle Sensor System





3-axis Angle Sensor System (Photo)



≻Size :≻16cm *13cm



Embedded in the Machine Tool















Z-offsets: 23cm & 27cm





Experimental Results



X Axis





Thank you for your attention